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(54) Title: METHODS AND APPARATUS FOR IDLE TIME REDUCTION IN A PRODUCTION FACILITY

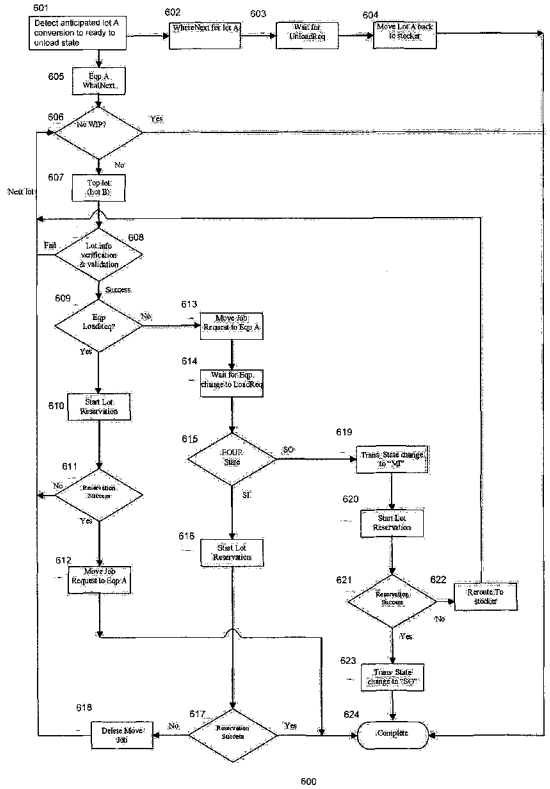

Figure 6

(57) Abstract: Efficient manufacturing automation system and methods are described. The automation system controls movement of materials for processing by tools in a manufacturing facility. The system and methods include pre-emptive dispatching for transferring of materials. With the pre-emptive dispatching, the next destination and next lot to be processed is determined prior to a first lot being converted to a ready to unload state. This reduces wait time or idle time to improve tool utilization.

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